30 DEC 2002

ABSTRACT OF THE DISCLOSURE

PROBE CONTACT SYSTEM HAVING PLANARITY ADJUSTMENT MECHANISM

A probe contact system is capable of adjusting distances between tips of the contactors and contact targets with simple and low cost mechanism. The planarity adjustment mechanism includes a contact substrate having a large number of contactors mounted on a surface thereof, a probe card for establishing electrical communication between the contactors and a test head of a semiconductor test system, a conductive elastomer provided between the contact substrate and the probe card, connection members for connecting the contact substrate and the probe card at three locations on the contact substrate where each of the connection members is adjustable for changing a distance between the contact substrate and the probe card, a gap sensor for measuring a gap between the contact substrate and a semiconductor wafer, and a rotation adjustment device for adjusting the connection member so that the gap between the contact substrate and the semiconductor wafer at each of the three locations becomes identical to one another.

FIG. 6

G00002

162162